3RS	4081∷	Search Text wafer and batch\$3 near1 process\$3	US-PGPUB, USPAT	2004/10/15 16:58	S1
3RS	5	S1 and workpiece and tool and state and metrology and rout\$3 and correlation	US-PGPUB; USPAT	2004/10/15 19:44	\$2
IS&R	1	("6773931").PN	US-PGPUB; USPAT; USOCR	2004/10/15 19:44	S3 -
3RS	1	S3 and fault	US-PGPUB; USPAT	2004/10/15:19:45	S4
BRS	1	S3 and (fault or error)	US-PGPUB; USPAT	2004/10/15 19:45	S5
ЗRS	1	S5 and detect\$3	US-PGPUB; USPAT	2004/10/15 19:51	S6
BRS	0	S3 and position	US-PGPUB; USPAT	2004/10/15 19:51	S7
BRS	0	S3 and modify\$3	US-PGPUB; USPAT	2004/10/15 19:52	.S8
BRS	0	S3 and queue	US-PGPUB; USPAT	2004/10/15 19:52	S9
3RS	0	S3 and sampl\$3	US-PGPUB; USPAT.	2004/10/15 19:53	S10
BRS.	0	S3 and trigger	US-PGPUB; USPAT	2004/10/15 19:53	S11
BRS	1	S3 and trigger\$3	US-PGPUB; USPAT	2004/10/15 19:53	S12
BRS	1	"6587744" PN	USPAT	2004/10/15 19:56	\$13
BRS	1	"6444481".PN	USPAT	2004/10/15 19:56	\$14
BRS	1	"6408220".PN	USPAT	2004/10/15 19:57	S15
BRS	1	"5270222" PN	USPAT	2004/10/15 19:57	S16
BRS	1	"6587744".PN	USPAT	2004/10/15 19:58	\$17

г	r c c	US 20040059456 A1	20040325	19	Correlating an inline parameter to a device operation parameter	700/121		Bode, Christopher A. et al :	P F G F (
c	១០១	US 20040029299 A1	20040212	20.	Dynamic targeting for a process control system	438/5	700/121	Pasadyn, Alexander J. et al.	ត្រភព
п	r c c	US 20010039462 A1	20011108	28	System and method for predicting software models using material-centric process instrumentation	700/45		Mendez, Rafael et al	k c c∶c (
c	ere	US 6773931 B2	20040810	19	Dynamic targeting for a process control system	438/10	700/121	Pasadyn, Alexander J et al.	жсссі
F	n c c	US 6650955 BI	20031118	9	Method and apparatus for determining a sampling plan based on process and equipment fingerprinting	700/108	438/14; 438/16; 438/17; 438/18; 700/109; 700/	Sonderman; Thomas J. et al.	гссгі

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